TOTTOTAL

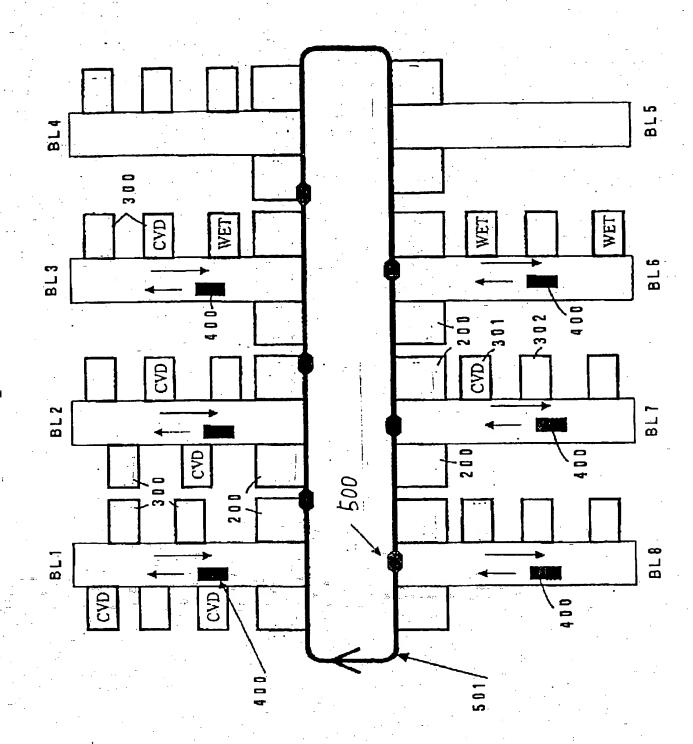


FIG. 2 prior art

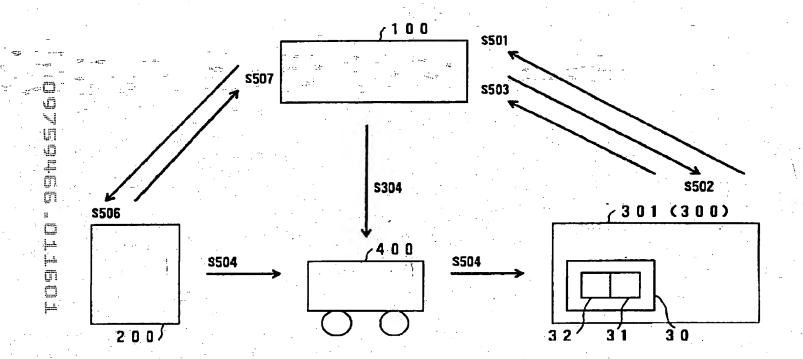
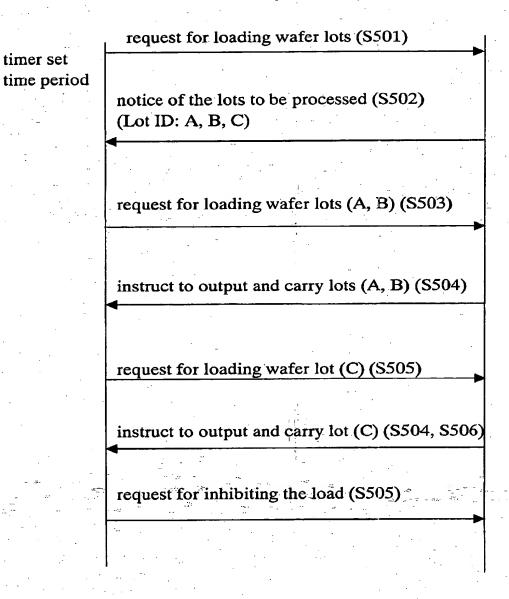


FIG. 3

low pressure CVD system

host computer



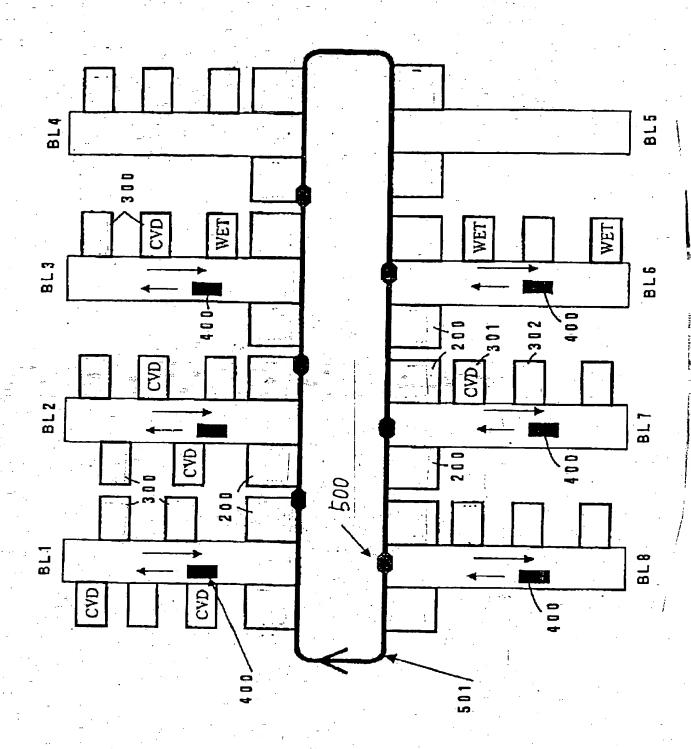
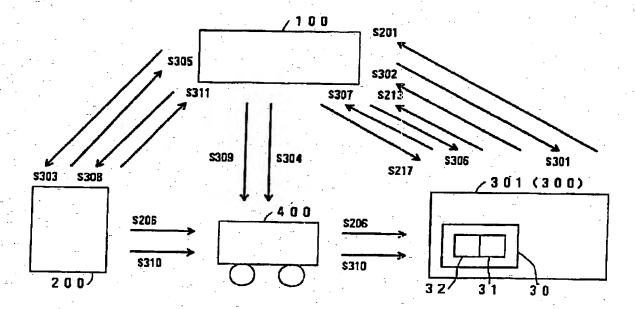


FIG. 5





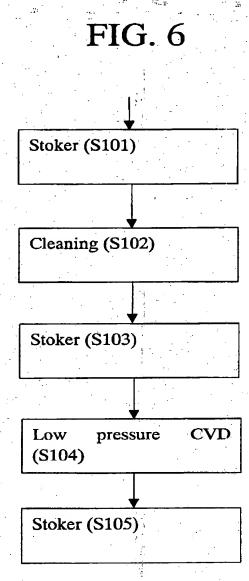
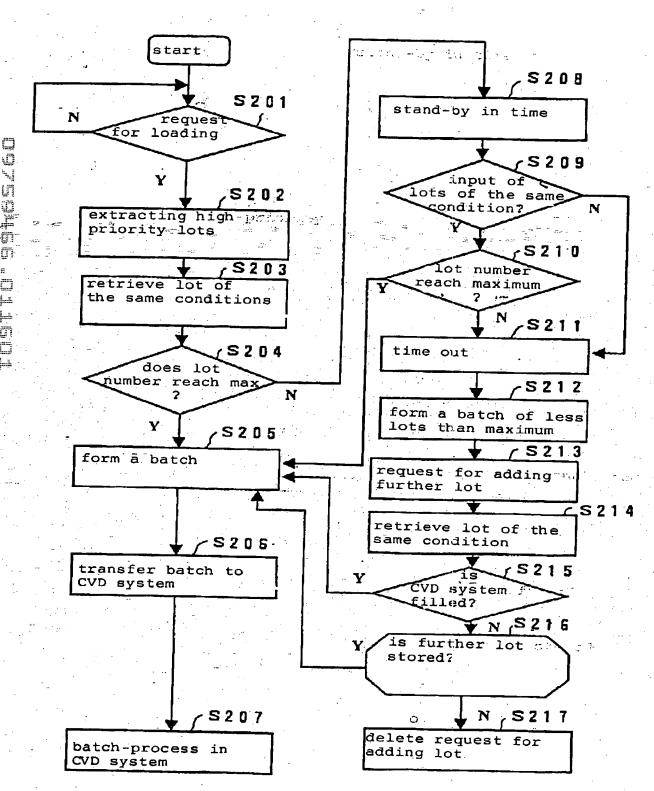


FIG. 7



low pressure CVD system

host computer

FIG. 8

request for loading wafer lots (S201)

timer set
time period

notice of the lots to be processed (S301)
(Lot ID: A, B, C)

request for loading wafer lots (A, B) (S302)

instruct to output and carry lots (A, B) (S303)
(S206)

request for loading wafer lot (C) (S302)

instruct to output and carry lot (C) (S303, S206)

request for additional loading (S213)

store new lot in stoker -

report for additional processing lot (D) (S306)

request for loading additional lot (D) (S307)

instruct to output and carry additional lot (D) (S308) (S310)

request for deleting request for loading additional lot (S217)

FIG. 9

